

Applicat	ion No	
Applicat	IOII IVO	•

09/982,830 Examiner

Toan Ton

Applicant(s)

KOMATSU, HIROSHI

Art Unit

2871

SEARCHED				
Class	Subclass	Date	Examiner	
349	141	8/4/2003	TTON	
	139			
	110			
	44			
	117			
			i	

INTERFERENCE SEARCHED				
Class	Subclass	Date	Examiner	

SEARCH NO (INCLUDING SEARC		·)
	DATE	EXMR
EAST liquid crystal parallel field, ips common lelectrode overlap\$5, overly\$4, overlaid\$4 incline\$2, angle black mask/matrix	8/4/2003	TTON